

WHAT IS CLAIMED:

1. A device comprising:

a housing;

one or more ion generators for generating ions of positive polarity
5 and ions of negative polarity;

one or more ion emitters for emitting ions of positive polarity and
ions of negative polarity;

wherein said one or more ion emitters is/are situated adjacent, but
outside said housing.

10 2. The device of claim 1, wherein said ions form an ion
concentration outside said housing and at a distance from a user's hair.

3. The device of claim 2, wherein said hair is encompassed by ,
said ion concentration.

4. The device of claim 1, further comprising at least one blower
15 for generating airflow to be applied to hair.

5. The device of claim 4, wherein said housing has at least one
aperture disposed therein forming an air outlet for directing said airflow.

6. The device of claim 5, wherein said one or more ion emitters
is/are situated at a distance from said airflow.

7. The device of claim 6, further comprising at least one attachment for cooperating with said air outlet to manipulate said airflow.

8. The device of claim 7, wherein said at least one attachment is configured to variably control aeration of said positive and negative ions
5 into said airflow.

9. The device of claim 8, wherein said at least one blower alters said airflow velocity, thereby controlling aspiration of said positive and negative ions into said airflow.

10. The device of claim 1, wherein said one or more ion
10 generators is/are configured to provide a variety of voltage outputs, as well as to generate combinations of positive and negative ions.

11. The device of claim 1, wherein said one or more ion emitters is/are positioned in a casing formed on said housing.

12. The device of claim 11, wherein said casing is selectively
15 removable from said housing.

13. The device of claim 1, wherein said one or more ion emitters is/are formed from a conductive metal.

14. The device of claim 1, wherein said one or more ion emitters is/are formed from a conductive polymer.

20 15. The device of claim 1, wherein said one or more ion emitters

is/are formed from a conductive silicon.

16. The device of claim 1, wherein said ion emitters form an array.

17. The device of claim 1, wherein said one or more ion emitters
5 create an ion concentration having a negative polarity.

18. The device of claim 1, wherein said one or more ion emitters create an ion concentration having a positive polarity.

19. The device of claim 1, wherein said one or more ion emitters create an ion concentration having both a positive and negative polarity.

10 20. The device of claim 1, wherein said ion emitters is/are arranged to generate a predictable area of concentrated ions and to minimize any dilution resulting from direct exposure to said airflow.

21. A method for treating hair comprising the steps of:

providing a device having a housing with at least one air outlet
15 disposed therein, a blower for generating an airflow stream, one or more ion generators, and one or more ion emitters disposed outside, but adjacent said housing and spaced a distance from said airflow exiting said air outlet;

applying said blower generated airflow toward hair for drying and/or
20 styling; and

generating an ion concentration having a certain area and spaced a certain distance from said airflow to minimize any dilution resulting from direct exposure to said airflow.

22. The method for treating hair of claim 21, further comprising
5 the step of providing at least one attachment for cooperating with said air outlet of said housing for controlling the mixing of said ion concentration with said airflow stream and hair.

23. The method for treating hair of claim 22, wherein said at least one attachment is configured to variably control aspiration of said positive
10 and negative ions into said airflow.

24. The method for treating hair of claim 23, wherein said at least one blower alters said airflow velocity, thereby controlling said aspiration of said positive and negative ions into said airflow.

25. The method for treating hair of claim 21, wherein said at least one ion generator is configured to provide a variety of voltage outputs, as
15 well as to generate combinations of positive and negative ions.

26. The method for treating hair of claim 21, wherein said one or more ion emitters is/are positioned in a casing formed on said housing.

27. The method for treating hair of claim 21, wherein said one or
20 more ion emitters is/are formed from a conductive metal.

28. The method for treating hair of claim 21, wherein said one or more ion emitters is/are formed from a conductive polymer.

29. The method for treating hair of claim 21, wherein said one or more ion emitters is/are formed from a conductive silicon.

5 30. The method for treating hair of claim 21, wherein said ion emitters form an array.

31. The method for treating hair of claim 21, wherein said one or more ion emitters create an ion concentration having a negative polarity.

10 32. The method for treating hair of claim 21, wherein said one or more ion emitters create an ion concentration having a positive polarity.

33. The method for treating hair of claim 21, wherein said one or more ion emitters create an ion concentration having both a positive and negative polarity.

15 34. The method for treating hair of claim 21, wherein said one or more ion emitters is/are arranged to generate a predictable area of concentrated ions and to minimize any dilution resulting from direct exposure to said airflow.